Special Issue

Advances in MEMS Magnetics for Emerging Applications

Message from the Guest Editors

The purpose of this call for a Special Issue in *Micromachines* is to assemble some of the recent works on MEMS magnetics. We hope to provide a collective resource for researchers and experts in the field as well as the broader scientific community. Therefore, we welcome contributions in the form of regular research papers, short communications, and review articles on all aspects of the four abovementioned topics, including but not limited to:

- Developments of MEMS/NEMS magnetic devices for emerging applications, including but not limited to integrated power electronics, wireless power transfer, implants, and biomedical applications.
- Design and modeling of novel MEMS/NEMS magnetic devices.
- Novel magnetic materials ranging from nanoparticle and composite to thin-film architectures.
- Novel integrated passive devices, such as inductors and transformers.
- MEMS magnetics for sensors, actuators, and energy harvesters.
- Process and packaging technology of magnetic materials towards CMOS-compatible integration.

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Deadline for manuscript submissions

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About the Journal

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

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